



Substitute for form 1449/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Complete if Known

Application No.:	10/549,865
Filing Date:	July 28, 2006
First Named Inventor:	Victor Higgs
Art Unit:	2886
Examiner Name:	Isiaka O. Akanbi
Attorney Docket No.:	NAN65 US (8037)

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U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Application of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear (if known)
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Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
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/I.A./	56.	Ribes, A.C. et al. (May 1, 1995). "Photoluminescence imaging of porous silicon using a confocal scanning laser microscope/microscope," <i>Applied Physics Letters</i> 66(18):2321-2323.	
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